



IFW

PATENT  
Customer No. 22,852  
Attorney Docket No. 4329.2821-01

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: )  
)  
Riichiro TAKAHASHI et al. ) Group Art Unit: 1752  
)  
Application No.: 10/824,482 ) Examiner: Richard L. Schilling  
)  
Filed: April 15, 2004 ) Confirmation No.: 6514  
)  
For: ALKALINE SOLUTION AND )  
MANUFACTURING METHOD, AND )  
ALKALINE SOLUTION APPLIED TO )  
PATTERN FORMING METHOD, )  
RESIST FILM REMOVING METHOD, )  
SOLUTION APPLICATION METHOD, )  
SUBSTRATE TREATMENT METHOD, )  
SOLUTION SUPPLY METHOD, AND )  
SEMICONDUCTOR DEVICE )  
MANUFACTURING METHOD )

Mail Stop Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

**REPLY TO OFFICE ACTION**

In reply to the Office Action mailed January 26, 2006, please amend the  
above-identified application as follows:

**Amendments to the Claims** are reflected in the listing of claims in this paper.

**Remarks** follow the amendment sections of this paper.